



LAM Research
490 AutoEtch Plasma Etch 150mm Configuration
SN 9164

LAM Research Autoetch 490 Plasma Etch



LAM 490 AutoEtcher

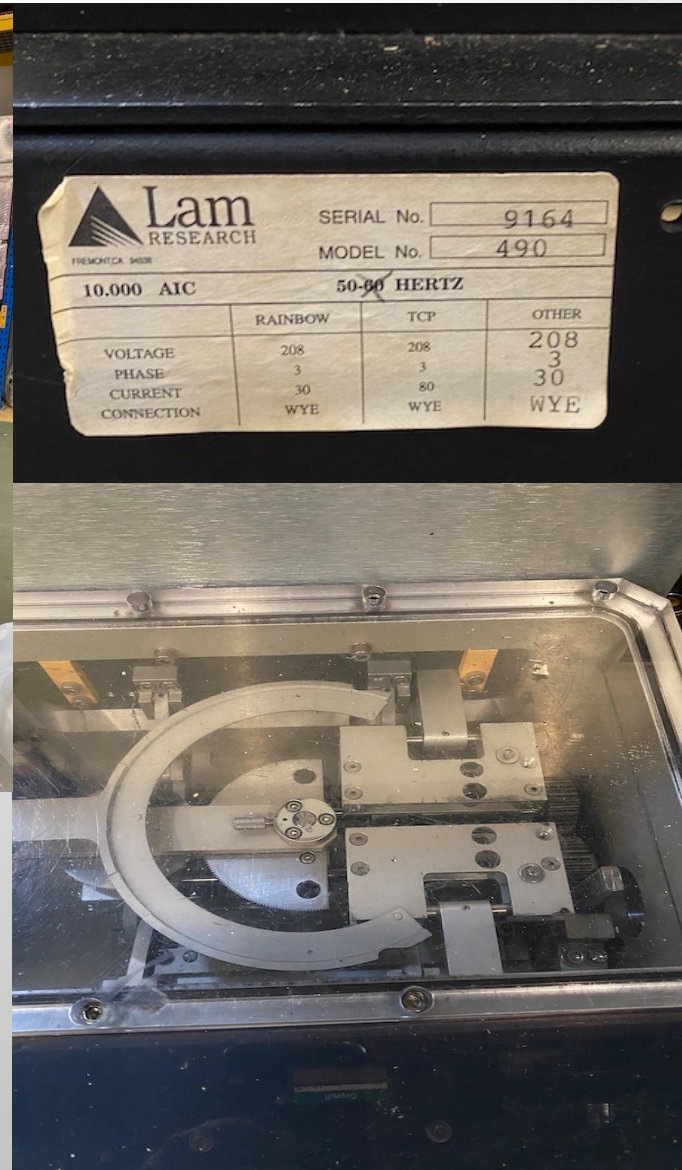
- Polysilicon: 490
- Wafer size: 6 inch
- Upgraded TFT monitors
- Incl maintenance console
- Conditon: AS IS (No Chiller, No pump but with ENI RF Generator)

Features:

- Single-wafer processing
- Fully automated microprocessor control
- Cassette-to-cassette wafer processing
- Vacuum load locked
- Programmable, variable electrode spacing
- Endpoint detection
- Configurable for 3-inch to 6-inch wafers
- Stand-alone or bulk-head mount configuration



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